19E. Smart Manufacturing and Machine Learning	
Session Date:	March 8(Wed.), 2023
Session Time:	15:15-16:40
Session Room:	Room E (#308 a)
Session Chair:	Dr. Han-Wool Yeon (Gwangju Institute of Science and Technology)

[19E-1] [Invited]   **15:15-15:40**

Next Generation Semiconductor Manufacturing Using Machine Learning, Process Models, Advanced Metrology and Equipment Intelligence®

David M. Fried

Lam Research

[19E-2]   **15:40-16:00**

ML-Assisted IC Test Binning with Real-Time Prediction at the Edge

Tomonori Honda, Thijs Haarhuis, Jeffrey D. David, Henri Hannink, Greg Prewitt and Vishnu Rajan

PDF Solutions Inc.

[19E-3]   **16:00-16:20**

Development of Outlier Detection Algorithms for Sensors with Time-Varying Characteristics

Chang Ho Lee, Jung Min Lee, Bo Bae Lee, Jae Seok Park, Ji Yeon Park, Young Hoon Kim and Jae Yong Park

Samsung Electronics Co., Ltd

[19E-4]   **16:20-16:40**

An Approach to Represent Time Series by Patterns and Process Dependent Statistics to Present Properties of Signals

Sunjung Kim, Chulhyun Park, Soohyun Chae, Minkyu Sohn, Changho Lee, Younghoon Kim and Jae-Yong Park

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